Hirotsugu Sugiura

List of Publications by Year in Descending Order

9 papers	42 citations	5 h-index	6 g-index
9 ext. papers	50 ext. citations	2.6 avg, IF	1.43 L-index

#	Paper	IF	Citations
9	Gas-phase and film analysis of hydrogenated amorphous carbon films: Effect of ion bombardment energy flux on sp2 carbon structures. *Diamond and Related Materials*, **2020**, 104, 107651	3.5	2
8	Facile synthesis of SnO2-graphene composites employing nonthermal plasma and SnO2 nanoparticles-dispersed ethanol. *Journal Physics D: Applied Physics*, **2019**, 52, 175301	3	8
7	Modifications of surface and bulk properties of magnetron-sputtered carbon films employing a post-treatment of atmospheric pressure plasma. *Japanese Journal of Applied Physics*, **2019**, 58, SAAC07	1.4	4
6	Effects of Ion Bombardment Energy Flux on Chemical Compositions and Structures of Hydrogenated Amorphous Carbon Films Grown by a Radical-Injection Plasma-Enhanced Chemical Vapor Deposition. *Journal of Carbon Research*, **2019**, 5, 8	3.3	1
5	Single-Step, Low-Temperature Simultaneous Formations and in Situ Binding of Tin Oxide Nanoparticles to Graphene Nanosheets by In-Liquid Plasma for Potential Applications in Gas Sensing and Lithium-Ion Batteries. *ACS Applied Nano Materials*, **2019**, 2, 649-654	5.6	5
4	Control of sp2-C cluster incorporation of amorphous carbon films grown by H-radical-injection CH4/H2 plasma-enhanced chemical vapor deposition. *Japanese Journal of Applied Physics*, **2019**, 58, 030912	1.4	6
3	Effects of gas residence time of CH4/H2 on sp2 fraction of amorphous carbon films and dissociated methyl density during radical-injection plasma-enhanced chemical vapor deposition. *Japanese Journal of Applied Physics*, **2018**, 57, 06JE03	1.4	5
2	Effect of gas residence time on near-edge X-ray absorption fine structures of hydrogenated amorphous carbon films grown by plasma-enhanced chemical vapor deposition. *Japanese Journal of Applied Physics*, **2016**, 55, 040305	1.4	3
1	Effects of Radical Species on Structural and Electronic Properties of Amorphous Carbon Films Deposited by Radical-Injection Plasma-Enhanced Chemical Vapor Deposition. *Plasma Processes and Polymers*, **2016**, 13, 730-736	3.4	8